

ABSTRACT

SUBSTRATE FOR MAGNETIC RECORDING MEDIUM

The present invention provides a surface-treated substrate for a magnetic recording medium, and a magnetic recording medium comprising a recording layer, wherein the surface-treated substrate can contain thick film which has adhesion strong enough to withstand leveling process such as polishing in the formation of film on the Si substrate. More specifically, the present invention provides a surface-treated substrate for a magnetic recording medium, comprising a Si substrate and a primer plating layer on the Si substrate, wherein the primer plating layer is film which comprises a metal and a Si oxide. Furthermore, the present invention provides a surface-treated substrate for a magnetic recording medium, comprising a Si substrate and a primer plating layer on the Si substrate, wherein at least 5 and at most 50 protrusions of a height of at least 100 nm per 100 μm^2 are present on a surface of the primer plating layer. Even further, the present invention provides a surface-treated substrate for a magnetic recording medium, comprising a Si substrate, a primer plating layer on the Si substrate and a soft magnetic layer above the primer plating layer, wherein a non-magnetic middle layer is provided between the primer plating layer and the soft magnetic layer.

Selected Drawing: Fig. 1